Abstract Submitted
for the GEC08 Meeting of
The American Physical Society

The effect of the ion-enhanced field emission on the CF_4 discharges in microgaps[1] MARIJA RADMILOVIC-RADJENOVIC, BRANISLAV RADJENOVIC, Institute of Physics, Belgrade-Serbia — Recently, much attention has been paid to studies on CF_4 due to its practical utility as a feed gas for plasma etching in the semiconductor industry. In order to reduced feature sizes on microelectronic devices, it is necessary to determine the breakdown voltage in microgaps. In this paper, semi-empirical expression for the breakdown voltage based on the numerical solutions of the equation that describes the DC breakdown criteria in CF_4 microdischarges has been suggested.

[1] The present work has been carried out under MNZŽS 141025 project.

Zoran Petrovic
Institute of Physics, Belgrade-Serbia

Date submitted: 06 Jun 2008 Electronic form version 1.4